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U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			
INFORMATION DISCLOSURE STATEMENT		Docket Number: 10901/36	
Application Number To be assigned	Filing Date Herewith	Examiner To be assigned	Art Unit To be assigned
Invention Title REFLECTOMETER AND METHOD FOR MANUFACTURING A REFLECTOMETER		Inventor(s) WEIDMANN et al.	


Assistant Commissioner for Patents
Washington D.C. 20231
Box Patent Application

- I. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicants hereby bring the references listed on the attached modified PTO Form No. 1449 to the attention of the Examiner. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
- II. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, except as otherwise indicated.

Dated:

2/5/02

By:


Richard L. Mayer (Reg. No. 22,490)

KENYON & KENYON
One Broadway
New York, N.Y. 10004
(212) 425-7200 (telephone)
(212) 425-5288 (facsimile)

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY. DOCKET NO. 10901/36	SERIAL NO. To be assigned
	APPLICANT WEIDMANN et al.	
	FILING DATE Herewith	GROUP To be assigned

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE*
	4,536,650*	Aug. 20, 1985	Carena et al.			
	4,644,156**	Feb. 17, 1987	Takahashi et al.			

* - If pertinent

* Cited in the attached German Search Report (copy enclosed).

** Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	40 06 789	Sept. 5, 1991	Germany			Abs., *	
	34 17 176	Nov. 21, 1985	Germany			Abs., *	
	34 16 864	Nov. 21, 1985	Germany			Abs., *	
	32 19 917	Dec. 23, 1982	Germany			Abs., *	
	0 240 776	Oct. 14, 1987	Europe			Abs., *	
	43 20 728	Jan. 12, 1995	Germany			**	
	0 511 597	Nov. 4, 1982	Europe			**	
	0 849 567	Jun. 24, 1998	Europe			**	
	2 072 850	Oct. 7, 1981	Europe			**	

* Cited in the attached German Search Report.

** Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

OTHER DOCUMENTS

EXAMINER INITIAL	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
	Zubel, I. et al., "Silicon anisotropic etching in alkaline solutions I. The geometric description of figures developed under etching Si(100) in various solutions," Sensors and Actuators A, vol. 70, no. 3, 1998, pp. 250-259.**
	Zubel, I. et al., "Silicon anisotropic etching in alkaline solutions II. On the influence of anisotropy on the smoothness of etched surfaces," Sensors and Actuators A, vol. 70, no. 3, 1998, pp. 260-268.**

** Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

EXAMINER	DATE CONSIDERED
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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